

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant:

Paul R. BERGER et al.

Conf.:

8252

Appl. No.:

09/934,334

Filed:

August 21, 2001

Group:

2811

Examiner:

Donghee KANG

For:

SI-BASED RESONANT INTERBAND TUNNELING DIODES AND

METHOD OF MAKING INTERBAND TUNNELING DIODES

## **LETTER REQUESTING INITIALED PTO 1449 FORMS**

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

May 17, 2004

Sir:

In reviewing the above-captioned application file, the undersigned has noted that acknowledgment was not received for the PTO 1449 Form filed with the Information Disclosure Statement on August 21, 2001.

Accordingly, a copy of the PTO Form 1449 not acknowledged is attached hereto. The Examiner is respectfully requested to return the initialed form to the undersigned as soon as possible.

If necessary, the Commissioner is hereby authorized in this, concurrent, and future replies, to charge payment or credit any overpayment to Deposit Account No. 02-2448 for any additional fees required under 37 C.F.R. § 1.16 or under 37 C.F.R. § 1.17; particularly, extension of time fees.

Respectfully submitted,

BIRCH, STEWART, KOLASCH & BIRCH, LLP

Michael K. Mutter, Reg.#29,680

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Attachments

3531-0103P

MKM/CAG:tm





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Form PTO-1449						3531-0103P Ne			PPLICATION NO. <b>EW</b>				
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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